

(19)



JAPANESE PATENT OFFICE

PATENT ABSTRACTS OF JAPAN

(11) Publication number: 06194230 A

(43) Date of publication of application: 15.07.94

(51) Int. Cl.

G01J 3/04

(21) Application number: 05245617

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(22) Date of filing: 30.09.93

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(54) SPECTROMETER SLIT MECHANISM

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(57) Abstract:

PURPOSE: To correctly monitor even if light quantity significantly changes according to slit widths, by adjusting the light quantity emitted and divided so as to be introduced into a monitor detector, with a diaphragm hole.

CONSTITUTION: A slid disk 1 is provided with diaphragm holes a, b, c, etc., for monitoring a light source. The beam emitted from an emission slit 2 is divided with a beam splitter 9, and then through diaphragm holes a, b, c, etc., made incident on a monitor photodetector 10. The diaphragm holes a, b, c, etc., are so arranged that they correspond to the emission slits 2 of respective widths, and that corresponding to the narrow slit 2 has a large aperture, and that corresponding to the wide slit 2 has a small aperture. The change of slit width significantly changes intensity of emitted light from a spectrometer, and monitor light is photo-detected through a diaphragm hole, switched along with switching of the slit 2, so, the monitor photodetector 10 of narrow dynamic range can be used.

